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#### U.S. PATENT AND TRADEMARK OFFICE

APPLICANT:

Kazuaki SUMITA et al.

SERIAL NO.:

10/808,329

FILED:

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FOR:

Liquid Epoxy Resin Composition and

Semiconductor Device

GROUP:

1712

**EXAMINER:** 

SELLERS, ROBERT E

## DECLARATION

Honorable Commissioner of Patents and Trademarks Washington, D.C. 20231

Sir,

- I, Kazuaki SUMITA, resident of c/o
  Silicone-Electronics Materials Research Center,
  Shin-Etsu Chemical Co., Ltd., 1-10, Hitomi,
  Matsuida-machi, Annaka-shi, Gunma-ken, Japan do hereby
  declare that:
- 1. I was graduated from Master Course of the Department of Material and Applied Chemistry of Nihon

University, Japan in March, 1992. Since 1992, I have been employed by Shin-Etsu Chemical Co., Ltd., the assignee of the above-identified application. I have been engaged in research and development relating to organic material (MC) in the laboratory of the Company

- 2. I am one of the named inventors of the above-identified application and hence, am familiar with the subject matter disclosed in said application.
- 3. In order to show the feature of the present invention, I conducted the following experiments.

#### [Experiments]

The components shown in Table 1 were mixed to uniformity on a three-roll mill to give various resin compositions. These resin compositions were examined by the following tests. The results are also shown in Table 1.

## [Viscosity]

The viscosity at 25°C was measured using a BH-type rotary viscometer at a rotational speed of 4 rpm.

### [Penetration test]

A polyimide-coated silicon chip of 10 mm  $\times$  10 mm was placed on a FR-4 substrate of 30 mm  $\times$  30 mm using spacers of approximately 50  $\mu$ m thick, leaving a gap therebetween. The resin composition was melted on a hot plate at 100°C and allowed to penetrate into the gap. The time taken until the gap was fully filled with the composition was measured.

#### [Void test]

A polyimide-coated silicon chip of 10 mm  $\times$  10 mm was placed on a FR-4 substrate of 30 mm  $\times$  30 mm using spacers of approximately 50  $\mu$ m thick, to form a flip chip package having a gap of approximately 50  $\mu$ m. The composition was introduced into the gap and cured thereat. Using a scanning acoustic microscope C-SAM (SONIX Inc.), the sample was inspected for voiding.

## [Toughness K<sub>1c</sub>]

The toughness  $K_{1c}$  at normal temperature was measured according to ASTM D5045.

## [Glass Transition Temperature (Tg)]

Using a sample of the cured composition measuring  $5\times5\times15$  mm, the glass transition temperature was measured with a thermomechanical analyzer at a heating rate of  $5^{\circ}$  C/min.

# [Coefficients of Thermal Expansion (CTE)]

Based on the Tg measurement described above, a coefficient of thermal expansion below Tg (CTE-1) was determined for a temperature range of 50 to 80°C, and a coefficient of thermal expansion above Tg (CTE-2) was determined for a temperature range of 200 to 230°C.

## [Bond strength test]

On a polyimide-coated silicon chip was rested a frustoconical sample having a top diameter of 2 mm, a bottom diameter of 5 mm and a height of 3 mm. It was cured at 150°C for 3 hours. At the end of curing, the sample was measured for (initial) shear bond strength. The cured sample was then placed in a pressure cooker test (PCT) environment of 121°C and 2.1 atm for 336 hours for moisture absorption. At the end of PCT test, shear bond strength was measured again. In each Example, five

samples were used, from which an average bond strength value was calculated.

#### [PCT peel test]

Apolyimide-coated 10×10 mm silicon chipwas stacked on a 30×30 mm FR-4 substrate using spacers of approximately 100 µm thick, to form a flip chip package having a gap of approximately 100 µm. An epoxy resin composition was introduced into the gap and cured thereat. The assembly was held at 30°C and RH 65% for 192 hours and then processed 5 times by IR reflow set at a maximum temperature of 265°C, before the assembly was checked for peeling. The assembly was then placed in a PCT environment of 121°C and 2.1 atm for 336 hours, before the assembly was checked for peeling. Peeling was inspected by C-SAM (SONIX Inc.).

## [Thermal shock test]

Apolyimide-coated  $10\times10\,\mathrm{mm}$  silicon chip was stacked on a  $30\times30\,\mathrm{mm}$  FR-4 substrate using spacers of approximately  $100\,\mathrm{\mu m}$  thick, to form a flip chip package having a gap of approximately  $100\,\mathrm{\mu m}$ . An epoxy resin composition was introduced into the gap and cured thereat.

-:

The assembly was held at 30°C and RH 65% for 192 hours and then processed 5 times by IR reflow set at a maximum temperature of 265°C. The assembly was then tested by thermal cycling between -65°C/30 minutes and 150°C/30 minutes. After 250, 500 and 750 cycles, the assembly was examined for peeling and cracks.

#### Components

C-100S:

diethyldiaminophenylmethane,

Nippon Kayaku Co., Ltd.

C-300S:

tetraethyldiaminophenylmethane,

Nippon Kayaku Co., Ltd.

Seikacure-S: 4,4'-diamine-dibenzen-sulfone. Wakayama Seika Kogyo Co., Ltd.

KAYAHARD AA:

Nippon Kayaku Co., Ltd.

bisphenol F-type epoxy resin, RE303S-L: Nippon Kayaku Co., Ltd.

MH700:

New Japan Chemical Co., Ltd.

YH307:

(Me is methyl group and i-Pr is iso-propyl group)

Japan Epoxy Resins Co., Ltd.

KBM403: silane coupling agent,

γ-glycidoxypropyltrimethoxysilane,
Shin-Etsu Chemical Co., Ltd.

## Spherical silica:

spherical silica having a maximum particle size of up to 24  $\mu m$  and an average particle size of 6  $\mu m$ 

Copolymer: the addition reaction product of

and

$$\begin{array}{c|c} CH_3 & CH_3 \\ \hline I \\ H\text{-SiO} & SiO \\ \hline CH_3 & CH_3 \\ \hline CH_3 & CH_3 \\ \end{array}$$

2E4MZ: 2-ethyl-4-methylimidazole,

Shikoku Chemicals Corporation

Solvent A: 2-ethoxyethyl acetate,

boiling point 156.3°C

Solvent B: 2-butoxyethylacetate, boilingpoint 192° C

<u>Table 1-1</u>

Component (pbw)		Invention									
		1	2	3	4	5	6	7	8	9	
C-100S		30			15			1.			
C-3008			35		20	25					
Seikacure-S				32		10					
KAYAHARD AA				-		1	35	32	35	32	
RE303S-L		70	65	68	65	65	65	68	65	68	
MH700											
YH307	YH307				1						
Spherical silica		150	150	150	150	150	150	150	150	150	
KBM403	KBM403							_			
Copolymer		4	4	4	4	4	4	4	0	0	
2E4MZ	2E4MZ										
Solvent A		3	3	3	3	3	3	3			
Solvent B									3	3	
Measure	ment results	<del>-</del>				<del></del>		-	•		
Molar ratio of liquid epoxy rasin (A) to aromatic amine curing agent (B): (A)/(B)		0.84	0.84	0.78	0.78	0.80	0.70	0.80	0.70	0.80	
Viscosity (Pa's @25°C)		75.6	56.6	66.3	72.5	73.4	22.0	20.5	14.6	13.1	
Void test		nil	nil	nil	nil	nil	nil	nil	nil	nil	
Toughness K <sub>le</sub>		4.3	4.2	4.1	4.3	4.2	3.9	4.2	3.8	4.0	
Tg (°C)		125	122	110	105	108	102	102	102	103	
CTE-1 (ppm/°C)		32	31	33	32	31	32	32	32	31	
CTE-2 (ppm/°C)		122	115	113	114	119	116	114	115	116	
PCT peel test	After 5 times of IR reflow at 265°C	no peeling	no peeling	no peeling	no peeling	no peeling	no peeling	no peeling	no peeling	no peeling	
	After PCT 336 hr	no peeling	no peeling	no peeling	no peeling	no peeling	no- peeling	no peeling	no peeling	no peeling	
Bond strength (kgf/cm²)	Initial	256	248	255	243	255	229	231	215	221	
	After PCT 336 hr	206	199	203	187	189	175	172	184	179	
Failure (%) after thermal shock	250 cycles	0	0	0	0	0	0	0	0	0	
	500 cycles	0	0	0	0	0	O	0	0	0	
test	750 cycles	0	0	0	0	0	0	0	0	0	

Table 1-2

Component (pbw)		Comparison								
		1	2	3	4	5	6			
C-100S			20	40	27		28.2			
C-300S										
Seikacu	re-S									
KAYAHARD AA			_	-		27				
RE3035-L		50	80	60	72	73	71.8			
мн700		30				-				
YH307		20								
Spherical silica		150	150	150	150	150	150			
KBM403		1.0				_				
Copolymer		4	4	4	4	4	4			
2E4MZ	2E4MZ						-			
Solvent A			3	3	3	3	3			
Solvent B										
Measure	ment results				·	•	•			
Molar ratio of liquid epoxy resin (A) to aromatic amine curing agent (B): (A)/(B)		-	1.12	0.55	1.00	1.00	0.95			
Viscosity (Pars @25°C)		28.4	64.3	108	66.8	12.4	66.8			
Void test		nil	nil	nil	nil	nil	nil			
Toughness K <sub>ic</sub>		2.6	3.4	2.9	3.3	3.4	3.3			
Tg (°C)		140	138	86	139	110	133			
CTE-1 (ppm/°C)		31	29 .	35	29	32	30			
CTE-2 (ppm/°C)		113	105	144	110	115	108			
PCT peel test	After 5 times of IR reflow at 265°C	peeled	no peeling	peeled	no peeling	no peeling	no peeling			
	After PCT 336 hr	peeled	peeled	peeled	no peeling	no peeling	peeled			
Bond strength (kgf/cm²)	Initial	182	198	133	205	215	159			
	After PCT 336 hr	95	95	56	121	154	73			
Failure (%) after thermal shock test	250 cycles	50	0	0	o	0	0			
	500 cycles	100	0	40	0	0	0			
	750 cycles	-	10	100	5	5	5			

T.1

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

Dated this  $2\pi day$  of Avg., 2006

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